

IN THE SPECIFICATION:

Page 2, delete lines 1 and 2 in their entirety.

Page 2, before line 3, insert the following heading, subheadings and paragraph:

Background of the Invention

Field of the Invention

The present invention relates to a charging voltage measuring device and an ion beam irradiating device having a charging voltage measuring device which is employed in a process or apparatus for making ion implantation, ion doping or plasma treatment on a substrate, or a process or apparatus for conveying or drying the substrate, in which there is a fear that the surface of the substrate is electrified.

Description of the Related Art

Pages 2-36 renumbered as pages 1-35, respectively.